ELSEVIER

Thin Solid Films 326 (1998) 263

thin solid films

Author Index of Volume 326

Aita, C.R. 106, 117
Alford, T.L. 227
An, H. 201
Arslanov, V.V. 223
Atashbar, M.Z. 238

Banks, A.D. 47
Bayliss, S.C. 194
Beamson, G. 194
Bender, M. 67, 72
Blanc, J.P. 245
Boxman, R.L. 134
Brusatin, G. 99
Bucescu, M. 256
Bulacovschi, V. 256
Byun, D. 151

Capecchi, S. 99
Chen, B. 201
Chen, G.H. 88
Chen, Y. 60
Choi, W.-K. 151
Clare, B.W. 160
Clarke, D.T. 194
Cornish, J.C.L. 160

Das, S.R. 143
Daube, C. 67, 72
Davis, R.F. 47
Doremus, R. 205
Duan, L.H. 251

Erickson, L.E. 143

Farouk, B. 154
Fick, J. 99
Finello, D. 47
Frankenberger, H. 67, 72

Gagina, I.A. 223
Gajdardziska-Josifovska, M. 106, 117
Germain, J.P. 245
Gohda, S. 51
Goldsmith, S. 134
Gong, B. 238
Grimberg, I. 134
Guglielmi, M. 99

Hauttmann, S. 175
Hefter, G.T. 160
Hölsä, J. 189
Hou, J. 201
Hu, X.W. 251
Huang, J. 217

Iriyama, K. 211

Jacob, W. 1
Jennings, P.J. 160
Jeong, J. 151
Juliet, P. 189

Kallithrakas-Kontos, N. 166
Kanniainen, T. 78
Kawai, T. 51
Kennedy, R.J. 63
Kim, H.-J. 151
Kim, Y.W. 56
Ko, D.-H. 56
Koh, S.-K. 151
Kondo, K. 83
Koski, K. 189
Kum, D.-W. 151
Kunze, T. 175
Kwok, R.W.M. 88

Lamb, R. 238
Lapsker, I. 134
Laursen, T. 227
Law, D. 194
Lee, M.Y. 56
Lee, N.I. 56
Lee, Y.H. 154
Leskelä, M. 78
Li, J.B. 251
Li, X.F. 251
Liang, Y. 217
Liu, S. 201
Liu, X. 171
Lopatin, C.M. 227
Lund, C.P. 160
Luo, J.L. 180

Ma, H.L. 60
Ma, J. 60
Mah, K.W. 233
Maleysson, C. 245
Man, W.K. 88
Martucci, A. 99
Matsuoka, N. 51
Moshohoritou, R. 166
Müller, J. 175

Nakashima, K. 211
Ng, G.I. 233
Ninni, V. 166

Ocker, B. 67, 72
Oki, S. 51
Ozaki, Y. 211

Park, D. 151
Parkinson, M. 194
Pauly, A. 245
Peters, C.J. 143
Pizziconi, V. 227

Raihel, A. 134
Rapoport, L. 134
Rice, P.M. 106, 117
Ritala, M. 78
Roberson, S.L. 47
Rusu, G.G. 256
Rusu, G.I. 256
Rusu, M. 256

Saloniemi, H. 78
Sano, H. 83
Sato, K. 83
Schofield, M.A. 106, 117
Schöllhorn, B. 245
Schryvers, D. 126
Seelig, W. 67, 72
Shen, J. 201
Stampe, P.A. 63
Stanciu, A. 256
Stollenwerk, J. 67, 72
Strohhöfer, C. 99
Sun, H.T. 238

Tanaka, H. 51
Toth, L. 126
Travitzky, N.A. 134
Tsangaraki-Kaplanoglou, I. 166

Ullmann, J. 43

Verma, A.L. 211

Wang, X.J. 251
Wang, Y.T. 251
Weiss, B.Z. 134
Wilmott, M. 180
Wlodarski, W. 238
Wong, S.P. 88

Xu, D.P. 251
Xu, D.-X. 143

Yan, H. 88
Yandouzi, M. 126
Yang, H. 251
Yang, M.Z. 180
Yang, T.L. 60
Yi, J.W. 154
Yoneyama, M. 211
Yoon, S.F. 233
Yuan, J. 92

Zhang, D.H. 60
Zhang, F. 171
Zhang, P.H. 233
Zhang, S. 92
Zhang, W. 92
Zhang, Z. 211
Zheng, H.Q. 233
Zheng, L.X. 251
Zhitomirsky, V.N. 134
Zotova, T.V. 223

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ELSEVIER

Thin Solid Films 326 (1998) 264–268

thin solid films

Subject Index of Volume 326

Alloys
TEM study of B2+$L1_2$ decomposition in a nanoscale Ni-rich Ni–Al film, 126
Aluminium
Investigation of the relationship between the reflectance and the deposited nickel and tin amount on the aluminium anodic oxide film, 166
Aluminium oxide
Voltage controlled reactive sputtering process for aluminium oxide thin films, 189
Amorphous materials
Simulation and analysis of X-ray photoemission and Auger valence band spectra of hydrogenated amorphous silicon, 160
Anodic oxidation
Investigation of the relationship between the reflectance and the deposited nickel and tin amount on the aluminium anodic oxide film, 166
Atomic force microscopy
Reactive ion (N_2^+) beam pretreatment of sapphire for GaN growth, 151
Auger electron spectroscopy
Simulation and analysis of X-ray photoemission and Auger valence band spectra of hydrogenated amorphous silicon, 160
Band structure
An analysis of photoluminescence voltage quenching and band structure of nanoporous silicon, 194
Biomaterials
Hydroxyapatite powders and thin films prepared by a sol-gel technique, 227
Carbon steel
Crevice corrosion behavior of A516-70 carbon steel in solutions containing inhibitors and chloride ions, 180
Chemical vapor deposition
Growth of Fe_3N films via chemical vapor deposition of iron acetylacetonate and anhydrous ammonia, 47
Reactive ion (N_2^+) beam pretreatment of sapphire for GaN Growth, 151
Cluster
Nozzle diameter effects on $CuInSe_2$ films grown by ionized cluster beam deposition, 83
Composite films
Effects of gas composition and r.f. power on properties of a–C:H/SiC:H composite films grown by plasma-enhanced chemical vapor deposition, 154
Conductivity
Influence of peripheral electron-withdrawing substituents on the conductivity of zinc phthalocyanine in the presence of gases. Part 1: reducing gases, 245
Copper
Optical absorption of island films of noble metals: wave length of the plasma absorption band, 205
Corrosion
Crevice corrosion behavior of A516-70 carbon steel in solutions containing inhibitors and chloride ions, 180
Crystallization
Nozzle diameter effects on $CuInSe_2$ films grown by ionized cluster beam deposition, 83
SiC formation and influence on the morphology of polycrystalline silicon thin films on graphite substrates produced by zone melting recrystallization, 175
Cubic boron nitride
Proposal of a novel in situ stress-reducing method for the growth of c-BN, 43
Deposition process
Growth of Fe_3N films via chemical vapor deposition of iron acetylacetonate and anhydrous ammonia, 47
Effect of O_2 pressure on the preferred orientation of TiO_2 films prepared by filtered arc deposition, 171
Voltage controlled reactive sputtering process for aluminium oxide thin films, 189
Electrical properties and measurements
Dependence of film composition and thicknesses on optical and electrical properties of ITO–metal–ITO multilayers, 67
Dependence of oxygen flow on optical and electrical properties of DC-magnetron sputtered ITO films, 72
Temperature dependence of the electrical conductivity and Seebeck coefficient of new poly(ester-syloxane)urethane elastomers in thin films, 256
Electrochemistry
Crevice corrosion behavior of A516-70 carbon steel in solutions containing inhibitors and chloride ions, 180
Electrodeposition
Electrodeposition of PbTe thin films, 78
Ellipsometry
Surface reactions during growth and erosion of hydrocarbon films, 1
Epitaxial growth
Growth of MgO on Si(100) and GaAs(100) by laser ablation, 63
Erbium
Active optical properties of erbium-doped GeO_2-based sol-gel planar waveguides, 99
Evaporation
The preparation of photoluminescent Si nanocrystal–SiO_X films by reactive evaporation, 92
TEM study of B2+$L1_2$ decomposition in a nanoscale Ni-rich Ni–Al film, 126
Film formation diagram

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Fabrication of high valence $Sr(Fe_{0.65}Co_{0.35})O_3$ film by a pulsed laser ablation technique, 51
Fourier transform infrared spectroscopy
Effect of O_2 pressure on the preferred orientation of TiO_2 films prepared by filtered arc deposition, 171
Monolayers and Langmuir–Blodgett films of yttrium stearate, 223
FTIR spectroscopy of rhodopsin
Langmuir–Blodgett films of rhodopsin: an infrared spectroscopic study, 238
GaAs
Growth of MgO on Si(100) and GaAs(100) by laser ablation, 63
Gallium nitride
Reactive ion (N_2^+) beam pretreatment of sapphire for GaN growth, 151
Gate-oxides
Gate-oxide integrity in metal-oxide-semiconductor structures with Ti-polycide gates for ULSI applications, 56
Gold
Optical absorption of island films of noble metals: wave length of the plasma absorption band, 205
Grain growth
Characterizations of SnO_2 thin films deposited on Si substrates, 88
Graphite
SiC formation and influence on the morphology of polycrystalline silicon thin films on graphite substrates produced by zone melting recrystallization, 175
Growth mechanism
Transmission electron microscopy study of zirconia–alumina nanolaminates grown by reactive sputter deposition. Part I: zirconia nanocrystallite growth morphology, 106
Low-temperature growth of cubic GaN by metalorganic chemical-vapor deposition, 251
Heat treatment
Thermal behavior of Langmuir–Blodgett films of 5-(4-*N*-octadecylpyridyl)-10,15,20-tri-*p*-tolylporphyrin studied by ultraviolet-visible and infrared spectroscopies, 211
Hydrocarbon films
Surface reactions during growth and erosion of hydrocarbon films, 1
In situ implantation
Proposal of a novel in situ stress-reducing method for the growth of c-BN, 43
Indium phosphide
Electrical and optical properties of InP grown by molecular beam epitaxy using a valved phosphorus cracker cell, 233
Infrared spectroscopy
Thermal behavior of Langmuir–Blodgett films of 5-(4-*N*-octadecylpyridyl)-10,15,20-tri-*p*-tolylporphyrin studied by ultraviolet-visible and infrared spectroscopies, 211
Integrated optics
Active optical properties of erbium-doped GeO_2-based sol-gel planar waveguides, 99
Interfaces
Crevice corrosion behavior of A516-70 carbon steel in solutions containing inhibitors and chloride ions, 180
Molecular recognition of nucleolipid amphiphile octadecanoyl ester of 1-(2-carboxyethyl) adenine to the complementary nucleobases. Part I: characterization of the monolayer behavior at the air/water interface and photodimerization in the Langmuir–Blodgett film matrix under ultraviolet irradiation, 217
Ion-solid interation
Surface reactions during growth and erosion of hydrocarbon films, 1
Iron
Growth of Fe_3N films via chemical vapor deposition of iron acetylacetonate and anhydrous ammonia, 47
Langmuir–Blodgett films
Thermal behavior of Langmuir–Blodgett films of 5-(4-*N*-octadecylpyridyl)-10,15,20-tri-*p*-tolylporphyrin studied by ultraviolet-visible and infrared spectroscopies, 211
Molecular recognition of nucleolipid amphiphile octadecanoyl ester of 1-(2-carboxyethyl) adenine to the complementary nucleobases. Part I: characterization of the monolayer behavior at the air/water interface and photodimerization in the Langmuir–Blodgett film matrix under ultraviolet irradiation, 217
Monolayers and Langmuir–Blodgett films of yttrium stearate, 223
Langmuir–Blodgett films of rhodopsin
Langmuir–Blodgett films of rhodopsin: an infrared spectroscopic study, 238
Laser ablation
Fabrication of high valence $Sr(Fe_{0.65}Co_{0.35})O_3$ film by a pulsed laser ablation technique, 51
Growth of MgO on Si(100) and GaAs(100) by laser ablation, 63
Lead telluride (PbTe)
Electrodeposition of PbTe thin films, 78
Light-sensitive films
Langmuir–Blodgett films of rhodopsin: an infrared spectroscopic study, 238
Luminescence
The preparation of photoluminescent Si nanocrystal–SiO_X films by reactive evaporation, 92
Magnetron sputtering
Transparent conducting ZnO:Al films deposited on organic substrates deposited by r.f. magnetron-sputtering, 60
Mechanical properties
Structure and mechanical properties of vacuum arc-deposited NbN coatings, 134
MgO
Growth of MgO on Si(100) and GaAs(100) by laser ablation, 63
MOCVD
Low-temperature growth of cubic GaN by metalorganic chemical-vapor deposition, 251
Molecular beam epitaxy
Electrical and optical properties of InP grown by molecular beam epitaxy using a valved phosphorus cracker cell, 233
Molecular recognition
Molecular recognition of nucleolipid amphiphile octadecanoyl ester of 1-(2-carboxyethyl) adenine to the complementary nucleobases. Part I: characterization of the monolayer behavior at the air/water interface and photodimerization in the Langmuir–Blodgett film matrix under ultraviolet irradiation, 217

Monolayers
Molecular recognition of nucleolipid amphiphile octadecanoyl ester of 1-(2-carboxyethyl) adenine to the complementary nucleobases. Part I: characterization of the monolayer behavior at the air/water interface and photodimerization in the Langmuir–Blodgett film matrix under ultraviolet irradiation, 217
Monolayers and Langmuir–Blodgett films of yttrium stearate, 223
Multilayers
Dependence of film composition and thicknesses on optical and electrical properties of ITO–metal–ITO multilayers, 67
Dependence of oxygen flow on optical and electrical properties of DC-magnetron sputtered ITO films, 72
Nanostructures
The preparation of photoluminescent Si nanocrystal–SiO_X films by reactive evaporation, 92
Transmission electron microscopy study of zirconia–alumina nanolaminates grown by reactive sputter deposition. Part I: zirconia nanocrystallite growth morphology, 106
Transmission electron microscopy study of zirconia–alumina nanolaminates grown by reactive sputter deposition. Part II: transformation behavior of tetragonal zirconia nanocrystallites, 117
An analysis of photoluminescence voltage quenching and band structure of nanoporous silicon, 194
NbN coatings
Structure and mechanical properties of vacuum arc-deposited NbN coatings, 134
Nitrides
Growth of Fe_3N films via chemical vapor deposition of iron acetylacetonate and anhydrous ammonia, 47
Low-temperature growth of cubic GaN by metalorganic chemical-vapor deposition, 251
Nucleolipid amphiphile
Molecular recognition of nucleolipid amphiphile octadecanoyl ester of 1-(2-carboxyethyl) adenine to the complementary nucleobases. Part I: characterization of the monolayer behavior at the air/water interface and photodimerization in the Langmuir–Blodgett film matrix under ultraviolet irradiation, 217
Optical amplification
Active optical properties of erbium-doped GeO_2-based sol-gel planar waveguides, 99
Optical properties
Dependence of film composition and thicknesses on optical and electrical properties of ITO–metal–ITO multilayers, 67
Dependence of oxygen flow on optical and electrical properties of DC-magnetron sputtered ITO films, 72
Optical absorption of island films of noble metals: wave length of the plasma absorption band, 205
Organic multiple quantum well structures
Fabrication and characterization of high quality organic multiple quantum well structures, 201
Organic substrates
Transparent conducting ZnO:Al films deposited on organic substrates deposited by r.f. magnetron-sputtering, 60
Organomatallic vapor deposition
Influence of peripheral electron-withdrawing substituents on the conductivity of zinc phthalocyanine in the presence of gases. Part 1: reducing gases, 245
Oxidation equilibrium
Fabrication of high valence $Sr(Fe_{0.65}Co_{0.35})O_3$ film by a pulsed laser ablation technique, 51
Oxide breakdown
Gate-oxide integrity in metal-oxide-semiconductor structures with Ti-polycide gates for ULSI applications, 56
Oxide reliabilities
Gate-oxide integrity in metal-oxide-semiconductor structures with Ti-polycide gates for ULSI applications, 56
Oxides
Transmission electron microscopy study of zirconia–alumina nanolaminates grown by reactive sputter deposition. Part I: zirconia nanocrystallite growth morphology, 106
Transmission electron microscopy study of zirconia–alumina nanolaminates grown by reactive sputter deposition. Part II: transformation behavior of tetragonal zirconia nanocrystallites, 117
Perovskite oxide
Fabrication of high valence $Sr(Fe_{0.65}Co_{0.35})O_3$ film by a pulsed laser ablation technique, 51
Phase transition
Transmission electron microscopy study of zirconia–alumina nanolaminates grown by reactive sputter deposition. Part II: transformation behavior of tetragonal zirconia nanocrystallites, 117
TEM study of B2+$L1_2$ decomposition in a nanoscale Ni-rich Ni–Al film, 126
Material aspects of nickel silicide for ULSI applications, 143
Phosphorus
Electrical and optical properties of InP grown by molecular beam epitaxy using a valved phosphorus cracker cell, 233
Plasma deposition
Surface reactions during growth and erosion of hydrocarbon films, 1
Plasma-enhanced chemical vapor deposition
Effects of gas composition and r.f. power on properties of a–C:H/SiC:H composite films grown by plasma-enhanced chemical vapor deposition, 154
Polymers
Temperature dependence of the electrical conductivity and Seebeck coefficient of new poly(ester-syloxane)urethane elastomers in thin films, 256
Porphyrin
Thermal behavior of Langmuir–Blodgett films of 5-(4-*N*-octadecylpyridyl)-10,15,20-tri-*p*-tolylporphyrin studied by ultraviolet-visible and infrared spectroscopies, 211
Quantum effects
Fabrication and characterization of high quality organic multiple quantum well structures, 201
Radio frequency power
Effects of gas composition and r.f. power on properties of a–C:H/SiC:H composite films grown by plasma-enhanced chemical vapor deposition, 154
Raman scattering
Nozzle diameter effects on $CuInSe_2$ films grown by ionized cluster beam deposition, 83
Reactive ion beam
Reactive ion (N_2^+) beam pretreatment of sapphire for GaN growth, 151
Reflection spectroscopy
Investigation of the relationship between the reflectance and

the deposited nickel and tin amount on the aluminium anodic oxide film, 166
Rhodopsin films
Langmuir–Blodgett films of rhodopsin: an infrared spectroscopic study, 238
Rhodopsin secondary structure
Langmuir–Blodgett films of rhodopsin: an infrared spectroscopic study, 238
Semiconductors
Electrical and optical properties of InP grown by molecular beam epitaxy using a valved phosphorus cracker cell, 233
Influence of peripheral electron-withdrawing substituents on the conductivity of zinc phthalocyanine in the presence of gases. Part 1: reducing gases, 245
Temperature dependence of the electrical conductivity and Seebeck coefficient of new poly(ester-syloxane)urethane elastomers in thin films, 256
Sensors
Influence of peripheral electron-withdrawing substituents on the conductivity of zinc phthalocyanine in the presence of gases. Part 1: reducing gases, 245
Silicides
Material aspects of nickel silicide for ULSI applications, 143
Silicon
Growth of MgO on Si(100) and GaAs(100) by laser ablation, 63
Simulation and analysis of X-ray photoemission and Auger valence band spectra of hydrogenated amorphous silicon, 160
An analysis of photoluminescence voltage quenching and band structure of nanoporous silicon, 194
Silicon carbide
SiC formation and influence on the morphology of polycrystalline silicon thin films on graphite substrates produced by zone melting recrystallization, 175
Silicon oxide
The preparation of photoluminescent Si nanocrystal–SiO_X films by reactive evaporation, 92
Silver
Optical absorption of island films of noble metals: wave length of the plasma absorption band, 205
SnO_2 thin films
Characterizations of SnO_2 thin films deposited on Si substrates, 88
SnO_2/Si heterojunction
Characterizations of SnO_2 thin films deposited on Si substrates, 88
Solar cells
Nozzle diameter effects on $CuInSe_2$ films grown by ionized cluster beam deposition, 83
Sol-gel
Active optical properties of erbium-doped GeO_2-based sol-gel planar waveguides, 99
Sputtering
Dependence of film composition and thicknesses on optical and electrical properties of ITO–metal–ITO multilayers, 67
Dependence of oxygen flow on optical and electrical properties of DC-magnetron sputtered ITO films, 72
$Sr(Fe,Co)O_3$ film
Fabrication of high valence $Sr(Fe_{0.65}Co_{0.35})O_3$ film by a pulsed laser ablation technique, 51
Stress
Proposal of a novel in situ stress-reducing method for the growth of c-BN, 43
Surface morphology
SiC formation and influence on the morphology of polycrystalline silicon thin films on graphite substrates produced by zone melting recrystallization, 175
Low-temperature growth of cubic GaN by metalorganic chemical-vapor deposition, 251
Surface pressure
Monolayers and Langmuir–Blodgett films of yttrium stearate, 223
Surface reactions
Surface reactions during growth and erosion of hydrocarbon films, 1
Surface structure
Thermal behavior of Langmuir–Blodgett films of 5-(4-*N*-octadecylpyridyl)-10,15,20-tri-*p*-tolylporphyrin studied by ultraviolet-visible and infrared spectroscopies, 211
Thin films
Electrodeposition of PbTe thin films, 78
Ti-diffusion
Gate-oxide integrity in metal-oxide-semiconductor structures with Ti-polycide gates for ULSI applications, 56
Ti-polycides
Gate-oxide integrity in metal-oxide-semiconductor structures with Ti-polycide gates for ULSI applications, 56
Ti-silicide
Gate-oxide integrity in metal-oxide-semiconductor structures with Ti-polycide gates for ULSI applications, 56
Titanium oxide
Effect of O_2 pressure on the preferred orientation of TiO_2 films prepared by filtered arc deposition, 171
Transmission electron microscopy
Transmission electron microscopy study of zirconia–alumina nanolaminates grown by reactive sputter deposition. Part I: zirconia nanocrystallite growth morphology, 106
Transmission electron microscopy study of zirconia–alumina nanolaminates grown by reactive sputter deposition. Part II: transformation behavior of tetragonal zirconia nanocrystallites, 117
TEM study of $B2+L1_2$ decomposition in a nanoscale Ni-rich Ni–Al film, 126
Material aspects of nickel silicide for ULSI applications, 143
Vacuum arc plasma gun
Structure and mechanical properties of vacuum arc-deposited NbN coatings, 134
Voltage quenching
An analysis of photoluminescence voltage quenching and band structure of nanoporous silicon, 194
X-ray diffraction
Effect of O_2 pressure on the preferred orientation of TiO_2 films prepared by filtered arc deposition, 171
Fabrication and characterization of high quality organic multiple quantum well structures, 201
Hydroxyapatite powders and thin films prepared by a sol-gel technique, 227
X-ray emission
Investigation of the relationship between the reflectance and the deposited nickel and tin amount on the aluminium anodic oxide film, 166

X-ray photoelectron spectroscopy
Simulation and analysis of X-ray photoemission and Auger valence band spectra of hydrogenated amorphous silicon, 160
An analysis of photoluminescence voltage quenching and band structure of nanoporous silicon, 194

ZnO:Al films
Transparent conducting ZnO:Al films deposited on organic substrates deposited by r.f. magnetron-sputtering, 60